

31040
09/829587
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Class	Subclass

PATENT NUMBER

U.S. UTILITY Patent Application

O.I.P.E.	PATENT DATE
<i>KW</i> SCANNED <i>Ed</i> <i>Q.A.</i> <i>Am</i>	

APPLICATION NO. 09/829587	CONT/PRIOR	CLASS 438 156	SUBCLASS 7.0 345.44	ART UNIT 1765 1763	EXAMINER <i>76225</i> <i>Ed</i>
APPLICANTS: Pavel Laptev					
TITLE: System for, and method of, etching a surface on a wafer					

PTO-2040
12/99

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